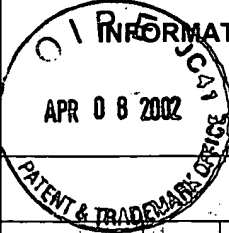
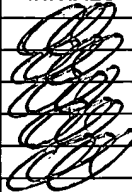


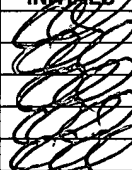
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	<b>INFORMATION DISCLOSURE STATEMENT</b> PTO Form 1449		<b>Docket Number</b> SJO920010040US1 501.388US01	<b>Serial Number</b> 10/038,125
	<b>Applicant(s)</b> CHOE			
	<b>Filing Date</b> 01/02/02		<b>Group Art Unit</b> 2652	

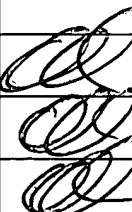
**U.S. PATENT DOCUMENTS**

EXAMINER INITIALS	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE (IF APPROPRIATE)
		5,764,056	6/9/98	Mao et al.	_____	_____	
		6,051,304	4/18/00	Takahashi	_____	_____	
		5,849,422	12/15/98	Hayashi	_____	_____	
		5,738,946	4/14/98	Iwasaki et al.	_____	_____	
		5,432,734	7/11/95	Kawano et al.	_____	_____	

**FOREIGN PATENT DOCUMENTS**

EXAMINER INITIALS	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
							YES	NO
		*JP 10-256621	9/25/98	Japan	_____	_____		
		*JP 11-87803	03/30/99	Japan	_____	_____		
		*JP 10-303477	11/13/98	Japan	_____	_____		
		*JP 9-245320	9/19/97	Japan	_____	_____		
		*JP 9-161243	06/20/97	Japan	_____	_____		

**OTHER DOCUMENTS**

		*Egelhoff, Jr. et al., "Oxygen as a Surfactant in the Growth of Giant Magnetoresistance Spin Valves," J. Appl. Phys., 82, December 15, 1997, pp. 6142-6151.
		*Tolkes et al., "Surfactant-Induced Layer-by-Layer Growth on a Highly Anisotropic Substrate: Co/Cu(110)," Physical Review Letters, Vol. 80, No. 13, March 30, 1998, pp. 2877-2880.
		*Geon Choe, "Giant interface magnetostriction and temperature dependence in NiFe films encapsulated with Ta and Al <sub>2</sub> O <sub>3</sub> layers," IEEE Trans. Mag. Vol. 35(5), p. 3838, 1999.

Examiner:

Date Considered:

9/10/03